

Searching PAJ

MENU**NEWS****HELP****Search Results : 188**

Index Indication

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Text SearchIf you want to conduct a Number Search, please click on
the button to the right.

Number Search

Applicant, Title of invention, Abstract --- e.g. computer semiconductor

If you use the AND/OR operation, please leave a SPACE between keywords.

One letter word or Stopwords are not searchable.

piezoelectric electrostrictive piezoceramic electromechanical

OR

AND

lamination laminated laminations laminating plies stack layers layered

OR

AND

"breakage layer"

AND

AND

Date of publication of application --- e.g. 19980401 - 19980405 -

AND

IPC --- e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.



Search

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RESULT LIST

0 results found in the Worldwide database for:

piezoelectric or electrostrictive or capacitor in the title AND **breakage near layer** in the title or abstract
(Results are sorted by date of upload in database)

Data supplied from the **esp@cenet** database - Worldwide

RESULT LIST

12 results found in the Worldwide database for:

piezoelectric or electrostrictive or capacitor in the title AND **crack* near layer** in the title or abstract
(Results are sorted by date of upload in database)

- 1 PIEZOELECTRIC/ELECTROSTRICTIVE DEVICE**
Inventor: IKEDA KOJI; SHIBATA KAZUYOSHI Applicant: NGK INSULATORS LTD
EC: H01L41/09G; H01L41/24 IPC: **H01L41/083; H01L41/09; H01L41/187** (+14)
Publication info: **JP2005072113** - 2005-03-17
- 2 LAMINATED PIEZOELECTRIC ELEMENT, MANUFACTURING METHOD THEREFOR, AND JETTING DEVICE**
Inventor: SETOGUCHI TAKESHI Applicant: KYOCERA CORP
EC: IPC: **H01L41/083; H01L41/09; H01L41/22** (+6)
Publication info: **JP2002289932** - 2002-10-04
- 3 CONTAINER FOR HOUSING PIEZOELECTRIC VIBRATOR**
Inventor: TAKATO TATSUJI Applicant: KYOCERA CORP
EC: IPC: **H01L23/02; H03H9/02; H03H9/10** (+6)
Publication info: **JP2002198767** - 2002-07-12
- 4 METHOD OF PRODUCING ELECTRIC DOUBLE LAYER CAPACITOR**
Inventor: SHIMIZU YASUSHIGE; NAKAO KEIICHI Applicant: MATSUSHITA ELECTRIC IND CO LTD
EC: IPC: **H01G9/058; H01G13/00; H01G9/058** (+3)
Publication info: **JP11329911** - 1999-11-30
- 5 PIEZOELECTRIC ELEMENT AND INK JET-TYPE RECORDER HEAD USING THE SAME**
Inventor: OKA HIROSHI; SUMI KOJI Applicant: SEIKO EPSON CORP
EC: IPC: **B41J2/045; B41J2/055; H01L41/09** (+9)
Publication info: **JP11214762** - 1999-08-06
- 6 CAPACITOR AND ITS MANUFACTURING METHOD**
Inventor: UNAMI KIYOSHI; SUZUKI KIYUJI; (+1) Applicant: MATSUSHITA ELECTRIC IND CO LTD
EC: IPC: **H01G4/18; H01G4/14; (IPC1-7): H01G4/18**
Publication info: **JP10261541** - 1998-09-29
- 7 LAMINATED PIEZOELECTRIC ACTUATOR ELEMENT AND MANUFACTURING METHOD THEREOF**
Inventor: KATOU TOMOYOSHI Applicant: CHICHIBU ONODA CEMENT CORP
EC: IPC: **H01L41/083; H01L41/22; H01L41/083** (+3)
Publication info: **JP9270540** - 1997-10-14
- 8 MANUFACTURE OF SOLID ELECTROLYTIC CAPACITOR**
Inventor: NISHIYAMA SUMIO; KOBASHI YASUHIRO; (+1) Applicant: MATSUSHITA ELECTRIC IND CO LTD
EC: IPC: **H01G9/032; H01G9/02; H01G9/022** (+2)
Publication info: **JP3178114** - 1991-08-02
- 9 LAMINATED PIEZOELECTRIC ELEMENT**
Inventor: SOMETSUGU TAKAHIRO; WATANABE JUNICHI; (+1) Applicant: HITACHI METALS LTD
EC: IPC: **H01L41/083; H01L41/09; H01L41/083** (+2)
Publication info: **JP2237083** - 1990-09-19
- 10 ELECTROSTRICTIVE EFFECT ELEMENT**
Inventor: UCHIUMI KAZUAKI; OCHI ATSUSHI; (+1) Applicant: NIPPON ELECTRIC CO
EC: H01L41/083 IPC: **H01L41/083; H01L41/083; (IPC1-7): H01L41/08**
Publication info: **JP1164080** - 1989-06-28



Results of searching in PCT for:

(piezoelectric or electrostrictive or electromechanical or capacitor) near (laminat* or plies or stack* or layer*) and (crack* or break*) near layer*: 108 records

Showing records 1 to 25 of 108 :

[\[Search Summary\]](#)[Next 25 records](#)[Start At](#) [Refine Search](#)

(piezoelectric or electrostrictive or electromechanical or



- | Title | Pub. Date | Int. Class | Applicant |
|--|------------|------------|--|
| 1. (WO 2007/040671) COG DIELECTRIC COMPOSITION FOR USE WITH COPPER ELECTRODES | 12.04.2007 | H01G 4/06 | FERRO CORPORATION |
| <p>Multilayer ceramic chip capacitors which satisfy COG requirements and which are compatible with reducing atmosphere sintering conditions so that non-noble metals such as copper and copper alloys thereof may be used for internal and external electrodes are made in accordance with the invention. The capacitors exhibit desirable dielectric properties (high capacitance, low dissipation factor, high insulation resistance), excellent performance on highly accelerated life testing, and very good resistance to dielectric breakdown. The dielectric layers comprise a composite oxide formed by calcining rare earth titanates, barium titanate, together with other metal oxides such as MgO, CaO, ZnO, MnO₂, ZrO₂, SiO₂, Ga₂O₃, Nd₂O₃, Nb₂O₅, and Y₂O₃.</p> | | | |
| 2. (WO 2007/037973) COG DIELECTRIC COMPOSITION FOR USE WITH NICKEL ELECTRODES | 05.04.2007 | C03C 3/14 | FERRO CORPORATION |
| <p>Multilayer ceramic chip capacitors which satisfy COG requirements and which are compatible with reducing atmosphere sintering conditions so that non-noble metals such as nickel and nickel alloys thereof may be used for internal and external electrodes are made in accordance with the invention. The capacitors exhibit desirable dielectric properties (high capacitance, low dissipation factor, high insulation resistance), excellent performance on highly accelerated life testing, and very good resistance to dielectric breakdown. The dielectric layers comprise a strontium zirconate matrix doped with other metal oxides such as TiO₂, MgO, B₂O₃, CaO, Al₂O₃, SiO₂, and SrO in various combinations. Figure 1 is a cross-sectional view of a multilayer cera...</p> | | | |
| 3. (WO 2007/024038) ELECTRO ACTIVE MATERIAL ACTUATOR EMBEDDED WITH INTERDIGITATED ELECTRODES | 01.03.2007 | H01L 41/08 | KONKUK UNIVERSITY INDUSTRIAL COOPERATION CORP. |
| <p>Disclosed is an actuator of electroactive material. The electroactive actuator (100) comprises: a thin film EAM layer (110); electrodes (120a and 120b) embedded in the EAM layer (110) and including a plurality of interdigitated electrodes (122a and 122b); and polymer layers (130a and 130b) deposited on the upper and lower surfaces of the EAM layer 110; wherein the interdigitated electrodes 122a and 122b are opposite each other in an interdigitated arrangement. In the disclosed actuator, an actuation effect several times higher than that of the prior art can be obtained using the interdigitated electrodes. Particularly when a single crystal piezoelectric material is used, the actuation effect can be further increased.</p> | | | |
| 4. (WO 2007/008986) METHOD AND APPARATUS FOR SCALABLE DROPLET EJECTION MANUFACTURING | 18.01.2007 | B41J 2/05 | FUJIFILM DIMATIX, INC. |
| <p>A method includes ejecting liquid having a first composition from a first droplet ejection deposition system that includes a first printhead and a first fluid source, collecting information on the behavior of the liquid under a variety of ejection conditions for the first droplet ejection deposition system, and ejecting liquid having the first material composition from a second droplet ejection deposition system that includes a second printhead and a second fluid source under the selected ejection conditions. The first printhead has a small number of flow paths, and the first fluid source is configured to hold a small volume of liquid. The second printhead has a plurality of substantially identical flow paths, each of the flow paths being s...</p> | | | |
| 5. (WO 2006/135495) PARTICLE PACKAGING SYSTEMS | 21.12.2006 | H01M 4/62 | MAXWELL |

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OR

AND

lamination laminated plies stack laminations

OR

AND

crack layer

AND

AND

Date of publication of application --- e.g. 19980401 - 19980405 -

AND

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One letter word or Stopwords are not searchable.

piezoelectric electrostrictive electromechanical

OR

AND

lamination laminated plies stack laminations

OR

AND

tensile stress

AND

AND

Date of publication of application --- e.g. 19980401 - 19980405

AND

IPC --- e.g. D01B7/04 A01C11/02

If you use the OR operation, please leave a SPACE between keywords.



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	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L1	340	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same (stress or strain)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_T DB	2007/04/16 10:50	
2	BRS	L2	1	"20060055288"	US-PGPUB	2007/04/16 08:55	
3	IS&R	L3	5	((("5200373") or ("6208026") or ("6798123") or ("6765337") or ("5835338"))).PN.	USPAT	2007/04/16 09:15	
4	BRS	L4	10	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same stress same crack\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_T DB	2007/04/16 09:13	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
5	BRS	L5	11	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same stress\$3 same crack\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/16 09:14	
6	BRS	L6	1	15 not 14	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/16 09:14	
7	BRS	L7	5	"5200373".uref.	USPAT	2007/04/16 09:16	
8	BRS	L8	7	"6208026".uref.	USPAT	2007/04/16 09:18	
9	BRS	L9	0	"6798123".uref.	USPAT	2007/04/16 09:18	
10	BRS	L10	1	"6765337".uref.	USPAT	2007/04/16 09:19	
11	BRS	L11	5	"5835338".uref.	USPAT	2007/04/16 09:19	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
12	BRS	L12	23	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same (stress or strain) and spacer	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 10:01	
13	BRS	L13	15	capacitor adj3 (plies or laminated or laminations or stack) same (stress or strain) and crack\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 09:38	
14	BRS	L14	6	gesemann-hans-juergen.in.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 10:02	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
15	BRS	L15	16	schoenecker-andreas.in.	US-PGPUB ; USPAT ; USOCR ; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 10:03	
16	BRS	L16	5	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same (stress adj2 layer)	US-PGPUB ; USPAT ; USOCR ; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 10:53	
17	BRS	L17	1	(piezoelectric or electrostrictive or electromechanical) adj3 (plies or laminated or laminations or stack) same stress and (break\$3 or crack\$3) adj2 layer	US-PGPUB ; USPAT ; USOCR ; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/04/1 6 10:53	